

## WEST Search History





DATE: Tuesday, January 09, 2007

| Hide?                    | <u>Set</u><br><u>Name</u>                       | <u>Query</u>   | <u>Hit</u><br><u>Count</u> |
|--------------------------|---|--|----------------------------|
|                          | <i>DB=PGPB,USPT; PLUR=YES; OP=ADJ</i>           |  |                            |
| <input type="checkbox"/> | L24   | L23 and l22  | 2                          |
| <input type="checkbox"/> | L23   | 134/94.1,95.2,99.1,102.1,102.3,105,107,902.ccls.<br>(apparatus or chamber) same (wafer or semiconductor or substrate or article)   | 4288                       |
| <input type="checkbox"/> | L22   | same pressur\$7 same temperature same (((releas\$3 or (fail shut) or bellow) with<br>(valve or element)))  | 81                         |
|                          | <i>DB=USOC; PLUR=YES; OP=ADJ</i>                |  |                            |
| <input type="checkbox"/> | L21   | (apparatus or chamber or autoclave) same dry\$3 same (wafer or semiconductor<br>or substrate or article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7<br>same temperature same (((releas\$3 or (fail shut) or bellow) with (valve or<br>element))) | 25                         |
| <input type="checkbox"/> | L20   | (apparatus or chamber or autoclave) same dry\$3 same (wafer or semiconductor<br>or substrate or article) same pressur\$7 same temperature same (((releas\$3 or (fail<br>shut) or bellow) with (valve or element)))   | 60                         |
|                          | <i>DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i> |  |                            |
| <input type="checkbox"/> | L19   | (apparatus or chamber or autoclave) same dry\$3 same (wafer or semiconductor<br>or substrate or article) same pressur\$7 same temperature same (((releas\$3 or (fail<br>shut) or bellow) with (valve or element)))   | 1                          |
|                          | <i>DB=PGPB,USPT; PLUR=YES; OP=ADJ</i>           |  |                            |
| <input type="checkbox"/> | L18   | (apparatus or chamber or autoclave) same dry\$3 same (wafer or semiconductor<br>or substrate or article) same pressur\$7 same temperature same (((releas\$3 or (fail<br>shut) or bellow) with (valve or element)))   | 8                          |
| <input type="checkbox"/> | L17   | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or<br>article) same pressur\$7 same temperature same (((releas\$3 or (fail shut) or<br>bellow) with (valve or element)))  | 6                          |
|                          | <i>DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i> |  |                            |
| <input type="checkbox"/> | L16   | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or<br>article) same pressur\$7 same temperature same (((releas\$3 or (fail shut) or<br>bellow) with (valve or element)))  | 1                          |
|                          | <i>DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ</i>      |  |                            |
| <input type="checkbox"/> | L15   | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or<br>article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7 same<br>temperature same (((releas\$3 or (fail shut) or bellow) with (valve or element)))                 | 28                         |
|                          | <i>DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i> |  |                            |
| <input type="checkbox"/> | L14   | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or<br>article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7 same<br>temperature same (((releas\$3 or (fail shut) or bellow) with (valve or element)))                 | 0                          |

|                          |     |  |       |
|--------------------------|-----|--|-------|
| <input type="checkbox"/> | L13 | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7 same temperature same (((releas\$3 or (fail shut)) with (valve or element))) | 0     |
| <input type="checkbox"/> | L12 | (apparatus or chamber) same dry\$3 same (wafer or semiconductor or substrate or article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7 same temperature same ((releas\$3 or (fail shut) with (valve or element)))   | 0     |
| <input type="checkbox"/> | L11 | (apparatus or chamber) same (wafer or semiconductor or substrate or article) same (hold\$3 or support\$3 or chuck\$3) same pressur\$7 same temperature same ((releas\$3 or bellows or (fail shut) with (valve or element)))    | 25    |
| <input type="checkbox"/> | L10 | (apparatus or chamber) same (wafer or semiconductor or substrate or article) same pressur\$7 same temperature same ((releas\$3 or bellows or (fail shut) with (valve or element)))   | 102   |
| <input type="checkbox"/> | L9  | (apparatus or chamber) same (wafer or semiconductor or substrate or article) same pressur\$7 same ((releas\$3 or bellows or (fail shut) with (valve or element)))  | 651   |
| <input type="checkbox"/> | L8  | (apparatus or chamber) same (wafer or semiconductor or substrate or article) same pressur\$7 same (releas\$3 or bellows or (fail shut))  | 651   |
|                          |     | <i>DB=USPT; PLUR=YES; OP=ADJ</i>   |       |
| <input type="checkbox"/> | L7  | 6896740.pn. or 5715612.pn.   | 2     |
|                          |     | <i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ</i>  |       |
| <input type="checkbox"/> | L6  | L5 and ((chamber or apparatus) same heat\$3 same pressur\$7 same releas\$3)  | 6     |
| <input type="checkbox"/> | L5  | L4 or l1 or l2   | 17838 |
| <input type="checkbox"/> | L4  | (dainippon screen).as.   | 17838 |
| <input type="checkbox"/> | L3  | (danippon screen).as.  | 4     |
| <input type="checkbox"/> | L2  | ozaki-hidehiko\$.in.   | 8     |
| <input type="checkbox"/> | L1  | nagami-shuzo\$.in.   | 12    |

END OF SEARCH HISTORY